

Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)			Complete if Known		
			Application Number	Not Yet Assigned <i>10/719,181</i>	
			Filing Date	Herewith <i>11-20-03</i>	
			First Named Inventor	Miller, David	
			Art Unit	Not Yet Assigned <i>2834</i>	
			Examiner Name	Not Yet Assigned <i>T. Dougherty</i>	
Sheet	1	of	3	Attorney Docket Number	019930-002820

U.S. PATENT DOCUMENTS+						
Examiner Initials*	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
<i>TMB</i>	AA	5,414,540		05/09/95	Patel et al.	<i>359 39</i>
<i>TMB</i>	AB	5,917,625		06/29/99	Ogusu et al.	<i>359 130</i>
<i>TMB</i>	AC	5,999,672		12/07/99	Hunter et al.	<i>385 37</i>
<i>TMD</i>	AD	6,028,689		02/22/00	Michalicek et al.	<i>359 224</i>
<i>TMD</i>	AE	6,040,935		03/21/00	Michalicek	<i>359 198</i>
<i>TMB</i>	AF	6,097,859		08/01/00	Solgaard'	<i>385 17</i>
<i>TMB</i>	AG	6,108,471		08/22/00	Zhang et al.	<i>385 37</i>
<i>TMB</i>	AH	6,128,122		10/03/00	Drake et al.	<i>359 224</i>
<i>TMB</i>	AI	09/442,061		11/16/99	Weverka, et al.	<i>- -</i>
	AJ	US-				
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	AL	US-				
	AM	US-				
	AN	US-				
	AO	US-				
	AP	US-				
	AQ	US-				
	AR	US-				
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	AT	US-				

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)			
	AU						<input type="checkbox"/>
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	AY						<input type="checkbox"/>
	AZ						<input type="checkbox"/>
	BA						<input type="checkbox"/>
	BB						<input type="checkbox"/>

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	<i>May 18, 2004</i>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Substitute for form 1449B/PTO		Complete if Known	
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Sheet 2	of 3	Attorney Docket Number	019930-002820

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
TMD	BC	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110	
TMD	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
TMD	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
TMD	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96	
TMD	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
TMD	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
TMD	BI	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
TMD	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
TMD	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985	
TMD	BL	P. Phillippe et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
TMD	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986	
TMD	BN	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
TMD	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
TMD	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142; No. 6, June 1995	
Examiner Signature	Thomas M. Dougherty		Date Considered May 18, 2004

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Sheet	3	of	3	Attorney Docket Number	019930-002820

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TMD		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
TMD		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
TMD		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000	

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